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SERIAL NUMBER 10/750,021	FILING DATE 12/30/2003 RULE	CLASS 438	GROUP ART UNIT 2823	ATTORNEY DOCKET NO. 51876P542
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APPLICANTS

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** CONTINUING DATA *****

NONE QVJ

** FOREIGN APPLICATIONS *****

REPUBLIC OF KOREA 2003-43071 06/30/2003 ✓ QVJ

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

** 05/04/2004

Foreign Priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS	TOTAL	INDEPENDENT
35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance		DRAWING 15	CLAIMS 20	CLAIMS 2
Verified and Acknowledged	<i>Quinton</i> Examiner's Signature <i>QVJ</i> Initials				

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TITLE

Method for fabricating semiconductor device having trench type device isolation layer

<input type="checkbox"/> All Fees
<input checked="" type="checkbox"/> 1.16 Fees (Filing)
<input type="checkbox"/> 1.17 Fees (Processing Ext. of

| FILING FEE FEES: Authority has been given in Paper |